

4a		1			()	
4b	4a	IVb-IVb'			,			
5a								,
5b	5a	Vb-Vb'			,			
6a								,
6b	6a	Ib- Ib'			,			
7a								,
7b	7a	VIIb-VIIb'			,			
8a								,
8b	8a	VIIIb-VIIIb'			,			
9		2			,			
10	11	9	X-X'	XI-XI'				
12a		2						
12b	12c	12a	XIIb-XIIb'	XIIc-XIIc'				,
13a	13b	12a	XIIb-XIIb'	XIIc-XIIc'			12b	12c
14a	13a	13b						,
14b	14c	14a	XIVb-XIVb'	XIVc-XIVc'				,
15a, 16a, 17a	15b, 16b, 17b	14a	XIVb-XIVb'	XIVc-XIVc'				,
	14b	14c						
18a	17a	17b						,
18b	18c	18a	XVIIIb-XVIIIb'	XVIIIc-XVIIIc'				,
19a	18a	18c						,
19b	19c	19a	XIXb-XIXb'	XIXc-XIXc'				,
20		3						.

가 가

가

1 2 1

1 1 2 1

1 (300) (100, 200) (200) (100) (100, 200)

(300) (310) 가 가 (13, 23) (350)

00) TN(twisted nematic) (100, 200) VA(vertically aligned) (100, 200)

(100) (110) 가 (Ag) (Ag alloy) (gate line)(121)

(Al alloy) (Cr), (Ti), (Ta) 가 가 (Al)

(121) (121) 가 가 (123)

20-80 °

(storage electrode)() (110) 가 ()

() () 가 .

(121) (SiNx) (gate insulating layer)(140)

(140) (hydrogenated amorphous silicon) (125)

(silicon island)(150)가 (150) 가 가 (silicide) n

(163, 165)가 n+ (165) (125) (ohmic contact)

(163) (150) (163, 165)

가 , 20-80 °

(163, 165) (140) (data line)(171)
 (drain electrode)(175) (177)가 (171)
 (175) Al Ag (121) (171)
 (171) 가 (171) (121)
 (175) (source electrode)(173) (173)
 (123) (163, 165)
 (177) (121)
 (171), (175) (177) 20-80° 가
 가
 (150) (171) (175) (163, 165)
 (171), (173) (177) 가 (150)
 (140) , (R, G, B)가 (R, G, B)
 (173) (177) (C1, C2) 가
 (R, G, B)가 (171) 가 (R, G,
 B) (121) (171) (125, 179)
 (R, G, B) (150)
 (R, G, B) SiOC SiOF
 4.0 가 (180) (180) (18)
 5, 187) 가 (175) (177) (185, 187)
 (R, G, B) (C1, C2) (R, G, B)
 가 가 (180) (171) (179)
 (189) 가 (140) (121) (125)
 (182) 가 (182, 189) (121) (171)
 ()
 (180) (187, 182, 185, 189) (C1, C2) 가 (tape
 r angle)
 (180) (185, 187) 30-180° (187, 185)
 (C1, C2) 가 (R, G, B) (C1, C2)
 (187, 182, 185, 189)
 (180) ITO(indium tin oxide) IZO(indium zinc oxide)
 (191) (191) (185)
 (187) (177) (175)
 (177) (121)
 (191) (200) (230)
 가
 (191)
 (191) (121) (171) (aperture)
 (180) (contact assistant)(192, 199)가 (192,
 199) (182, 189) (121) (171) (125, 179)
 (192, 199) (121) (171) (125, 179)

(192) . (192, 199)

21) (171) (121) / (171) (125, 179) (140) /
 (180) (metal island) (192, 199) ,

, (100) (200) , (110) (210)
 (121) (171) 가 , (220)가

(220) , , (150)

(220)가 (210) (191)
 (230)

, (350) (220) (23) , (350)
 (300) (310) (355)가
 (300) 가 , (100, 200)
 (13, 23) (310) (300) (310) (100, 200)
 (310) , (200) (310) (355) (355) (310)
 , (355) 가 ,

(100, 200) (350) (220)

, (200,) (100,

, 3a 3c

3a (210) , (200) ,
 (220) 가 , (220) 1.5-3.0 μ m 가

, 3b (230) , (210) ITO IZO

, 3c (220) , (350)
 (355) (100, 200) (cell gap) 4.0 μ m (220)
 1.5 μ m) 가 , (350)가 2.5 μ m 가 , (355) (355) (350)
 (350) 가 가 , (355)

, 2 , (210) (23) .
 (355) (350)

(350) (220) (350)
 , (350) (355) ,

8b, 1, 2, 4a

4a 8a, 4b 8b 4a 8a
 IVb-IVb', Vb-Vb', VIb-VIb', VIIb-VIIb', VIIIb-VIIIb'

4a 4b (110) (121)

5a 5b (140), (140) (150)
 (doped amorphous silicon island)(160)

6a 6b (173) (171), (171)
 (175) (177) (160) (160)

가 (163, 165) (150) (15)

0) () 7a 7b (C1, C2)

가 (R, G, B)

8a 8b (180) (140)
 (177) (187, 182, 185, 189) (175) (C1, C2)
 (185, 187) (R, G, B) (C1, C2) (180)
 (185, 187) (R, G, B) (185, 187)

(185, 187) (C1, C2) (185, 187) (C1, C2)

1 2, 1400 1600 ITO IZO (13)
 (192) (192, 199)

5 4 1

9 11 2

9 2 10 11 9
 X-X' XI-XI' 9 10 11

가 1

9 11 2 (110)
 (121) (131) (28) (121) 가 (121)
 (191) (175) (131) 가 (131)
 (191) (121) (140) 가 (131)
 가 (152) (163, 165)가

(152) (C) (171) (171) (175) (175)

(152) (C) (171) (175)

(121), (131), (152) (163, 165) 가 .

가 (185) (C1) (185) (C1)

, 9 (220) (171) 가

, (350)

11 12a 19c 9

12a 12b 12c

12a XIIb-XIIb' XIIc-XIIc' 13a 13b 12a

XIIb-XIIb' XIIc-XIIc' , 12b 12c , 1

4a 13a 13b , 14b 14c 14a XIV

b-XIVb' XIVc-XIVc' , 15a, 16a, 17a 15b, 16b, 17b 14

a XIVb-XIVb' XIVc-XIVc' 14b 14c

c 18a 17a 17b , 18b 18

18a XVIIIb-XVIIIb' XVIIIc-XVIIIc' , 19a 18a

18c 19b 19c 19a XIXb-XIXb'

XIXc-XIXc'

, 12a 12c , 1,000 3,000

(121) (131)

, 13a 13b , (140), (150), (160)

1,1600 5,000 , 1600 2,000 , 11400 600

(170) 1,1600 3,000

(210) 1 μm 2 μm

, (210) , 14b 14c , 가

1 (212) 2 (214) (212, 214) ,

(C) 2 (214) (A) 1 (212) 가 , (C) , 2

(B) (210) 가 (C)

(214) (A) 1 (212)

, 2 (214) 1 (212) 1/2 ,

, 4,000

, 가 가

(transparent area) (light blocking area) (translucent area)

(slit) (lattice pattern) 가

olution) 가 가 (res

, 15a 15b (B) (170) (170)

(160)

(170) 가 (212, 214) CeNH₃ 가 178

, 16a 16b (B) (160)

(150) (178) 2 (214)
 2 (214) (160) (ashing) (150) 152 (150) (C) 가 ,
 168 (160) (C) (178) (152) 가 (168) ,
 17a 17b (C) (178) (152) 가 가 (168) ,
 17b 1 (212) (C) (178) (171) (175) (163)
 (C) (168) (171) (175) (163)
 (165) (A) 1 (212) (C) (178) (168)
 (171) (175) , 18a 18c (178)
 R, G, B) (C) 가 (178)
 (C) 가 (178)
 (110) (R, G, B) (180) (171) (125, 179)
 (140) (182, 189, 185) (121) (171) (125, 179)
 (175) (13) , 1400 1600 (191) (175)
 9 11 (13) (171, 173, 175, 179) (173)
 192, 199) 2 1 (163, 165) (152) (175)
 (175) (173)
 1 2 가 1 2 가 (twisted nematic)
 1 가 1 2 가 (twisted nematic)
 20 3 (171, 173, 175, 179) (173)
 20 2 (171, 173, 175, 179) (173)
 , 1 , (210) 가 (R), (G), (B) 가 ,
 가 가 가 가 가

(57)

1.

가

2.

1

3.

2

4.

1

5.

1

6.

5

7.

5

8.

5

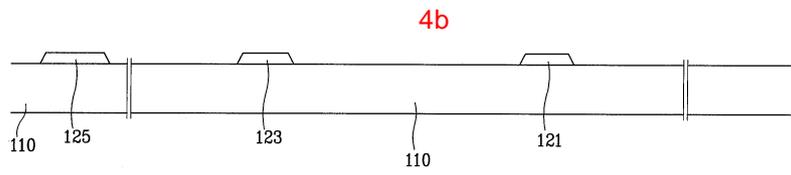
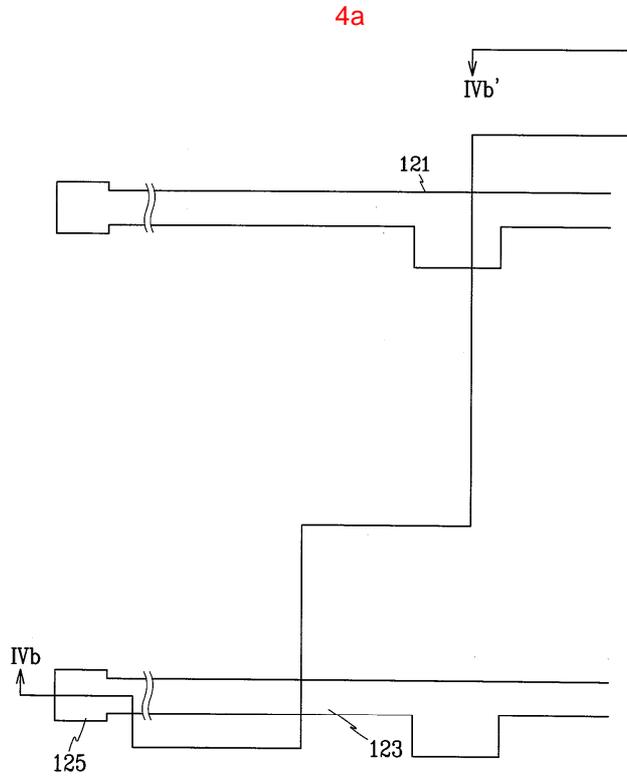
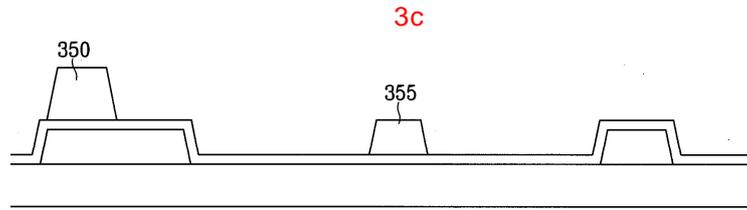
8 9.
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5 10.
,

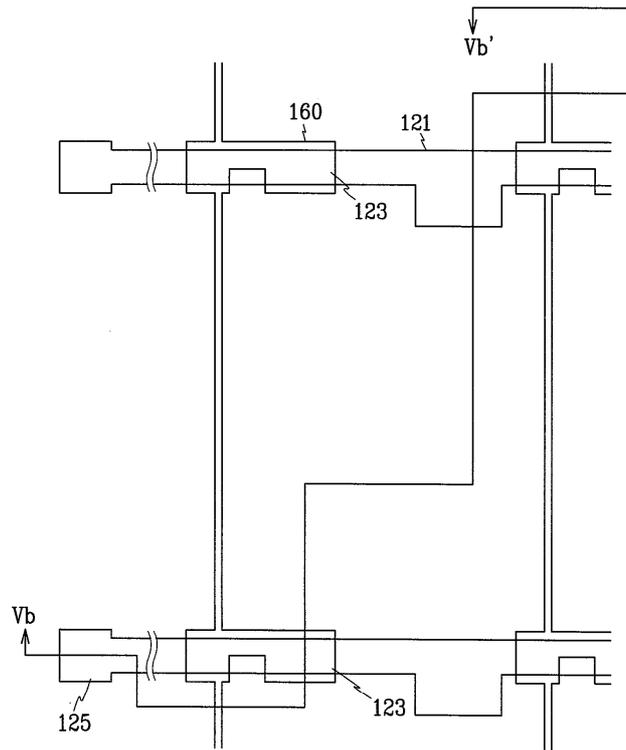
5 11.
,

12.
, 1 μm

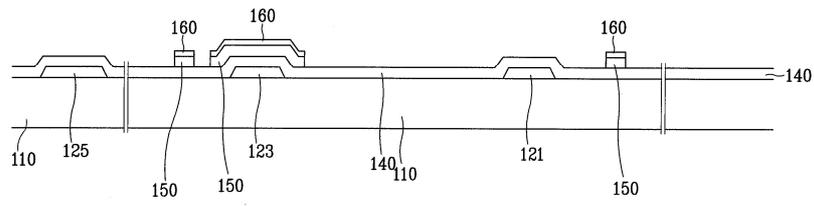
12 13.
,



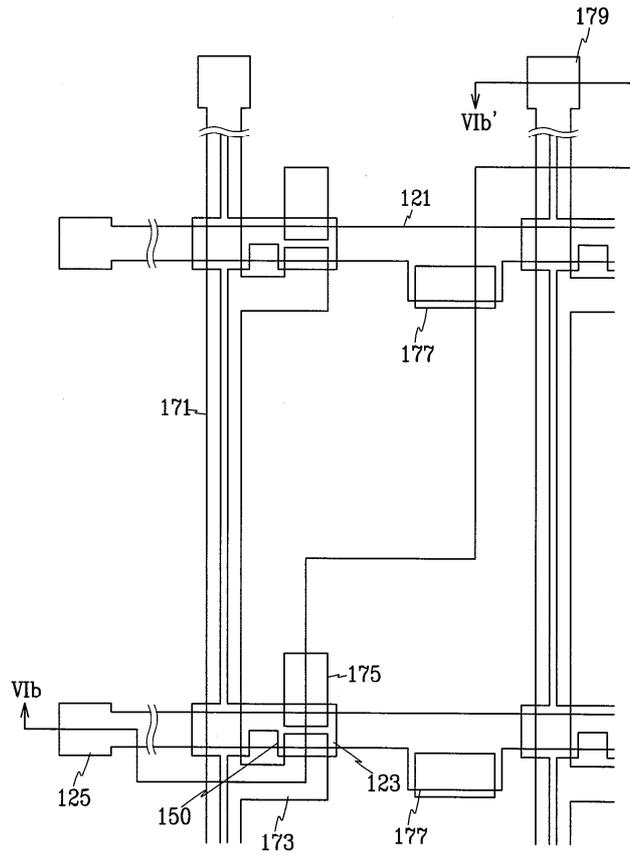
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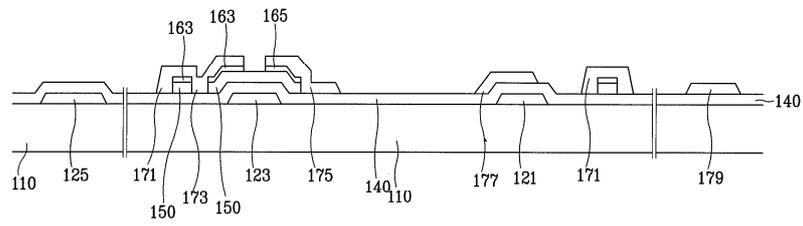
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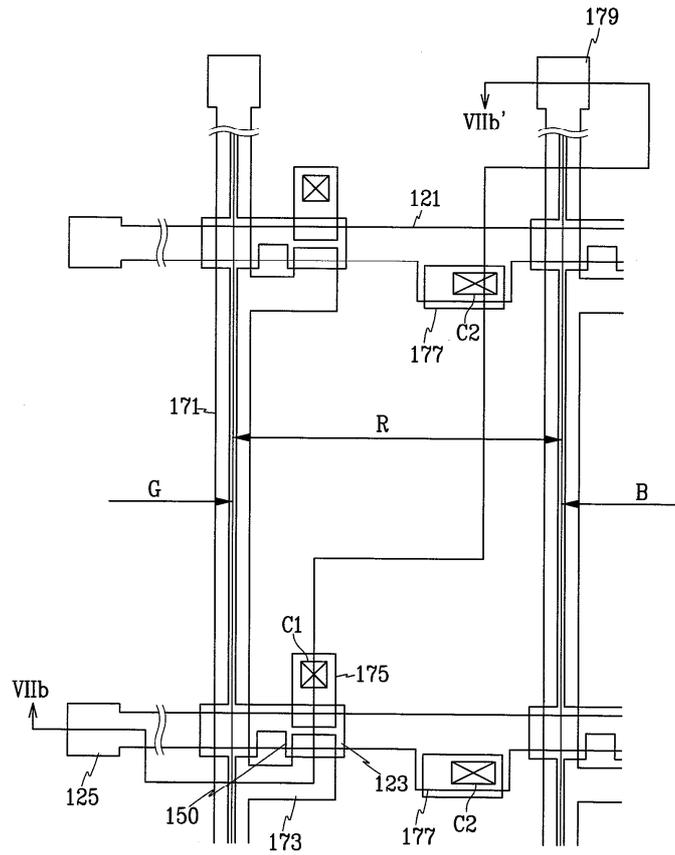
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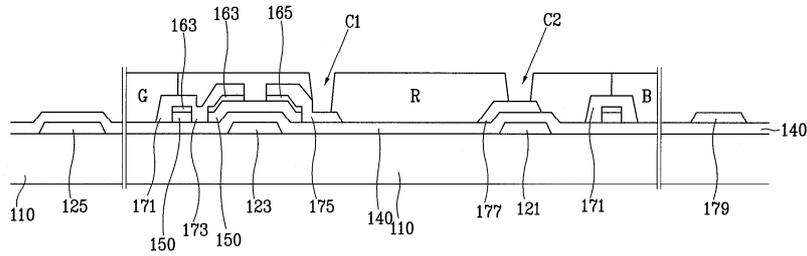
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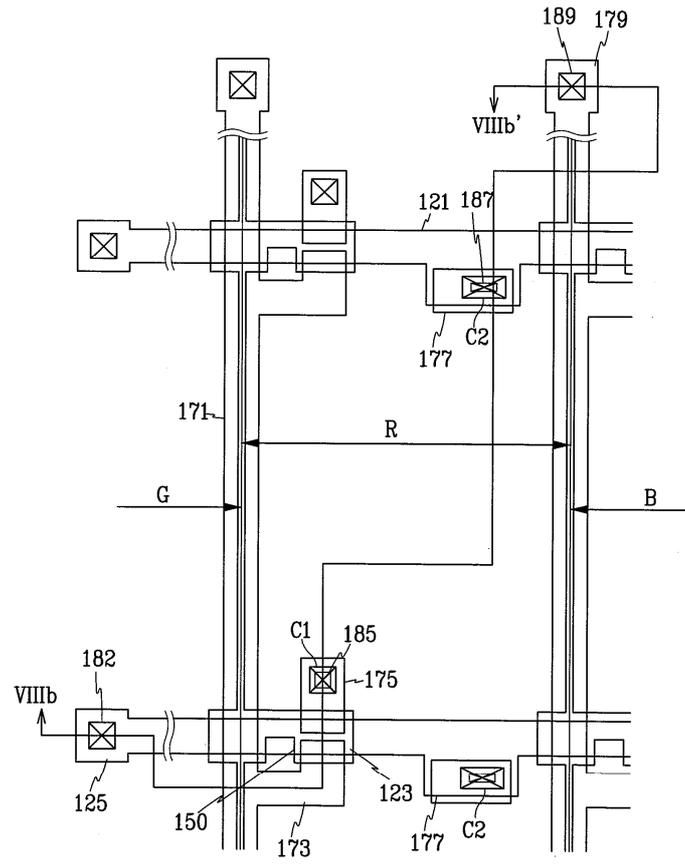
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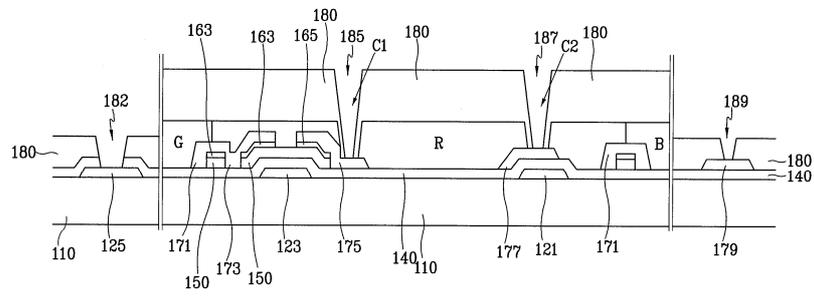
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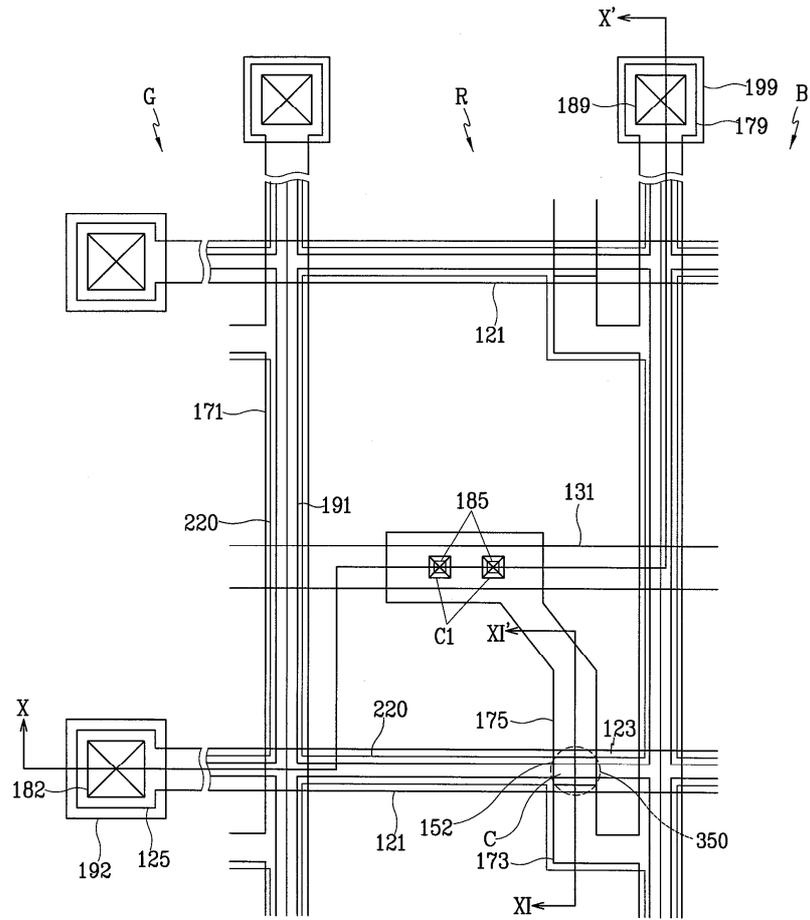
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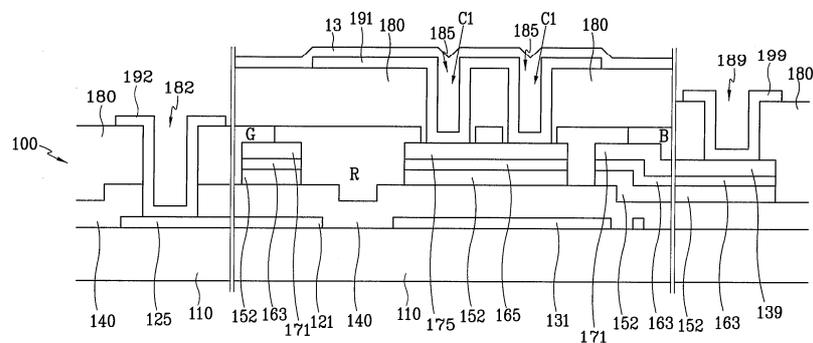
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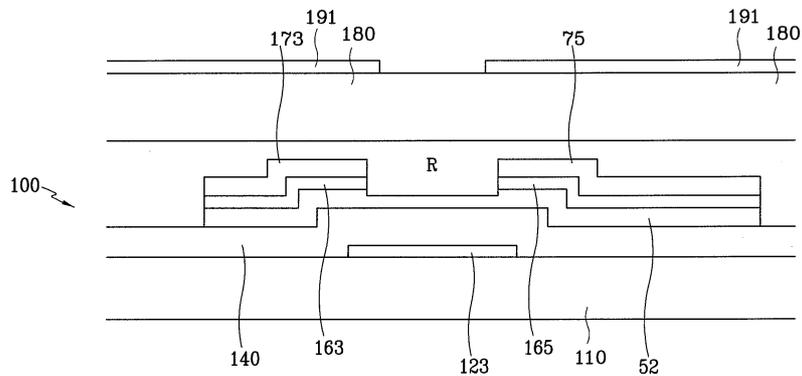
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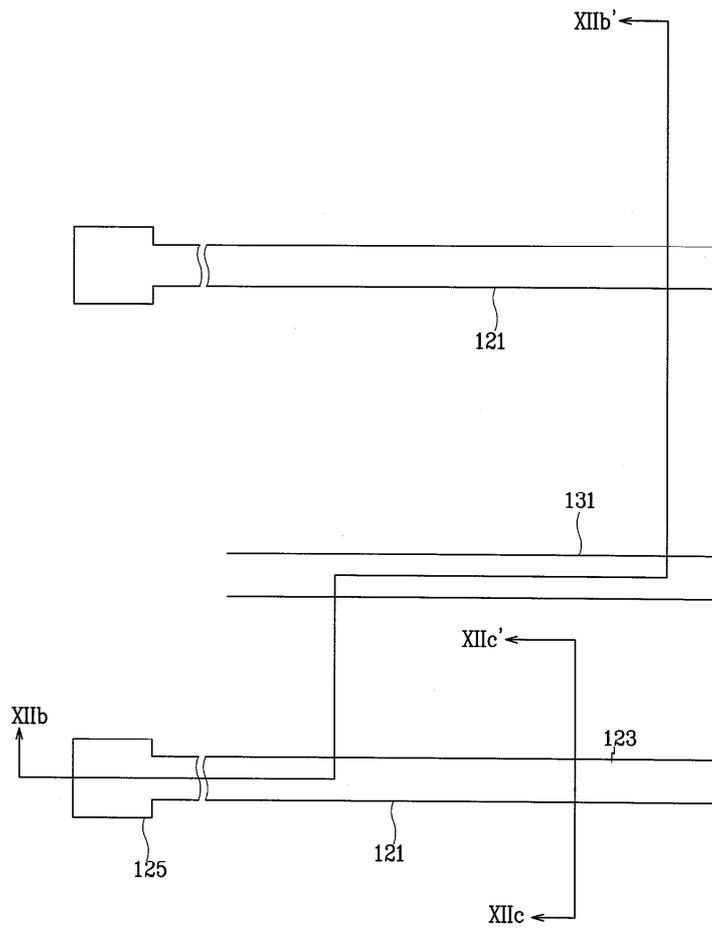
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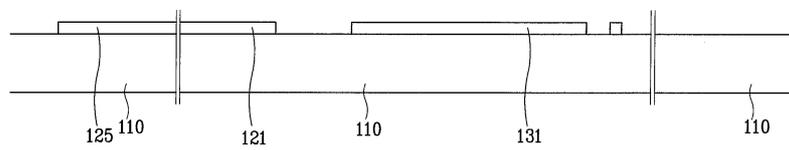
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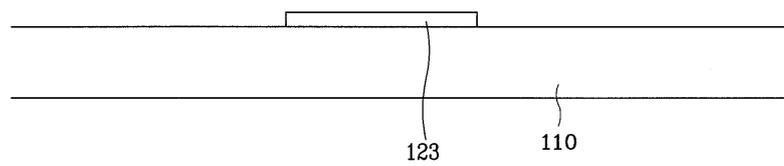
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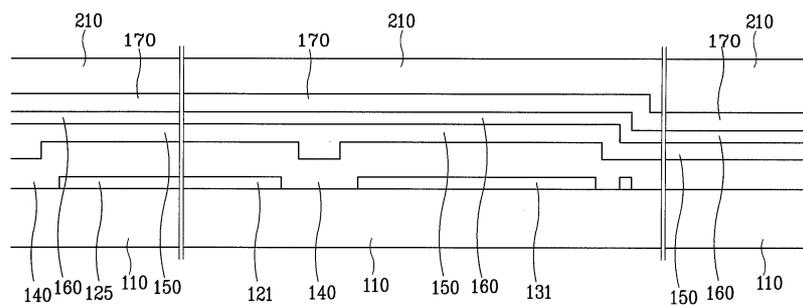
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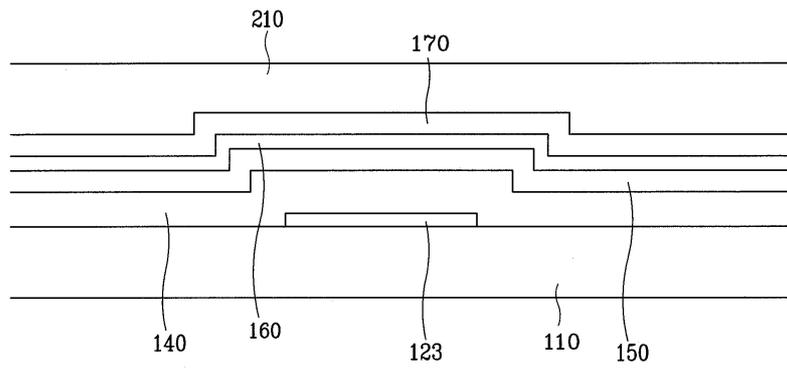
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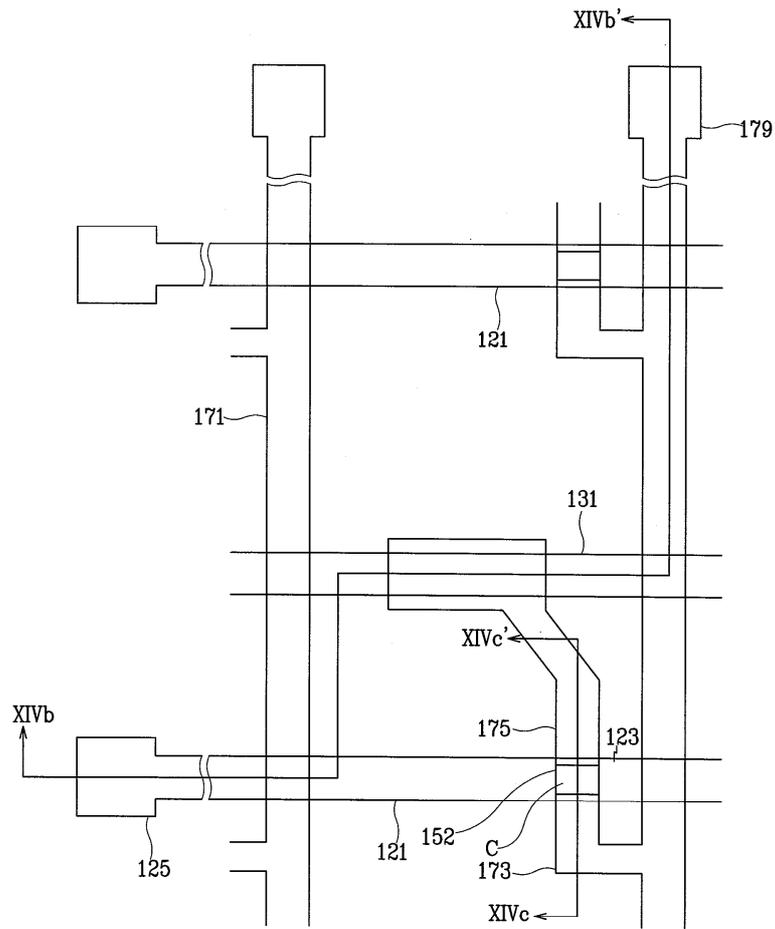
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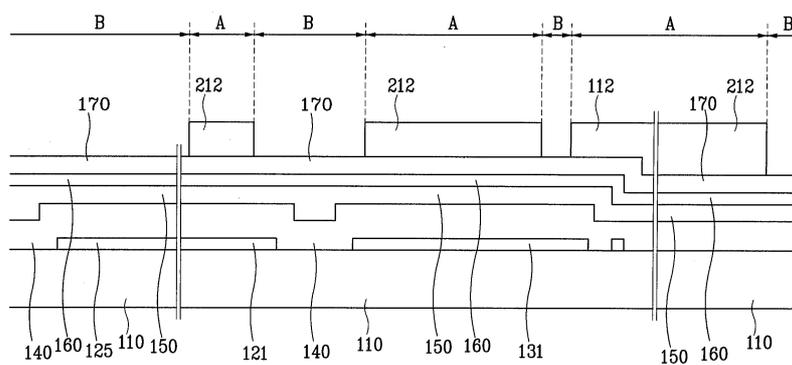
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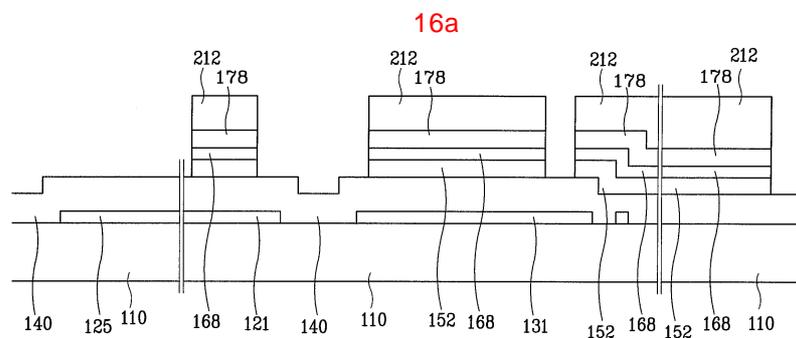
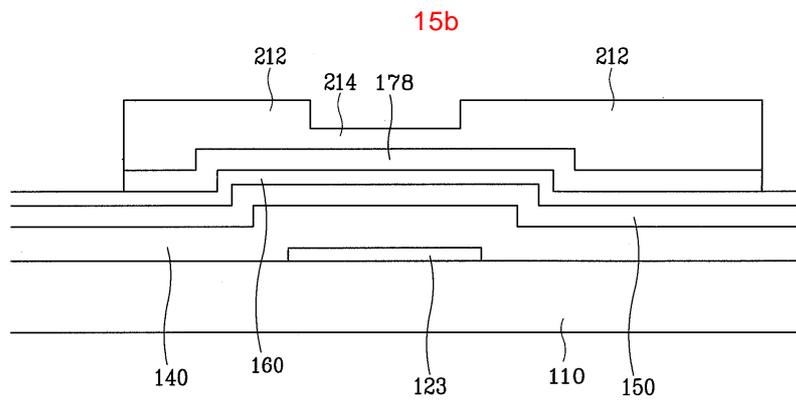
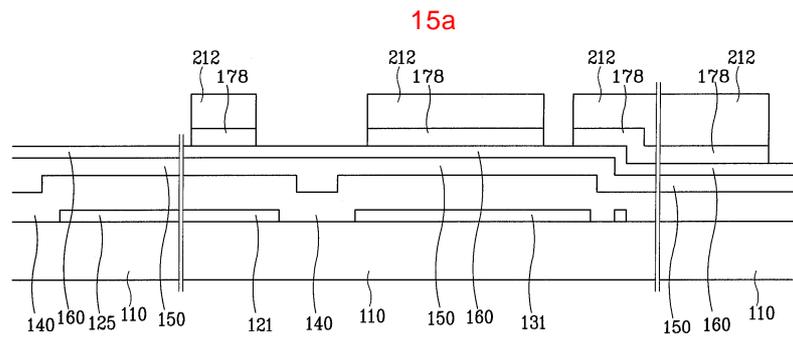
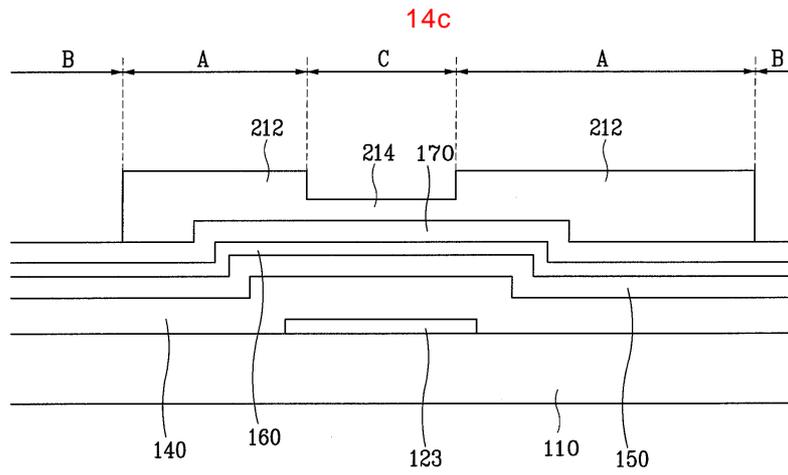


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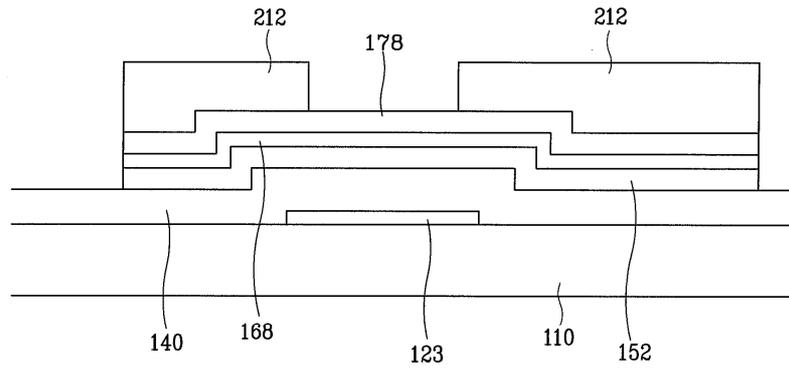


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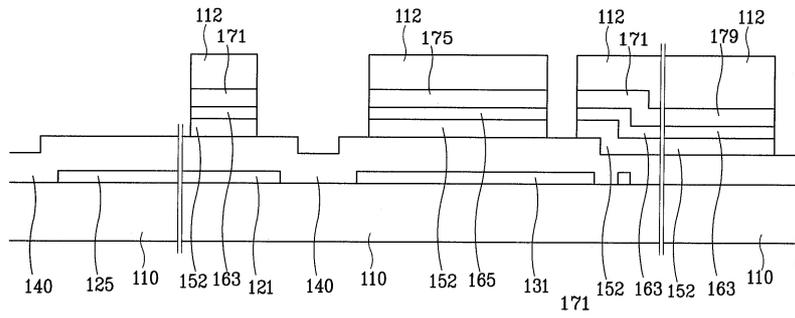




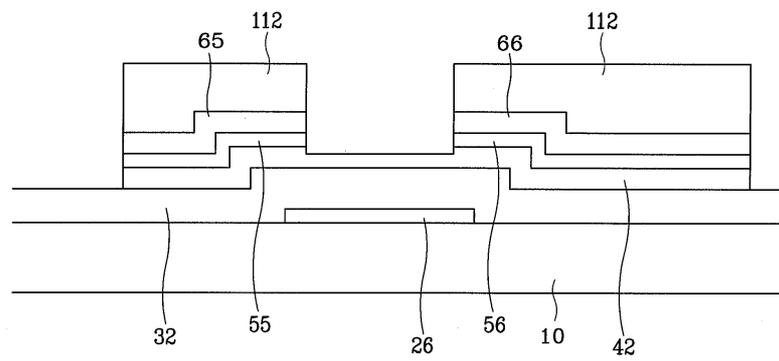
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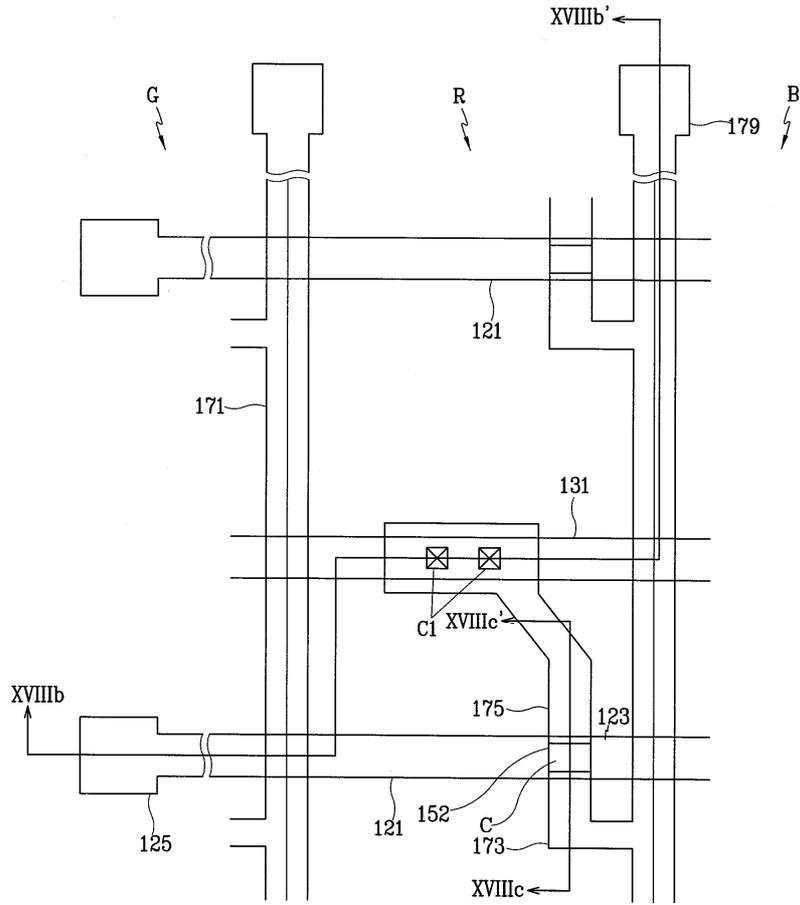
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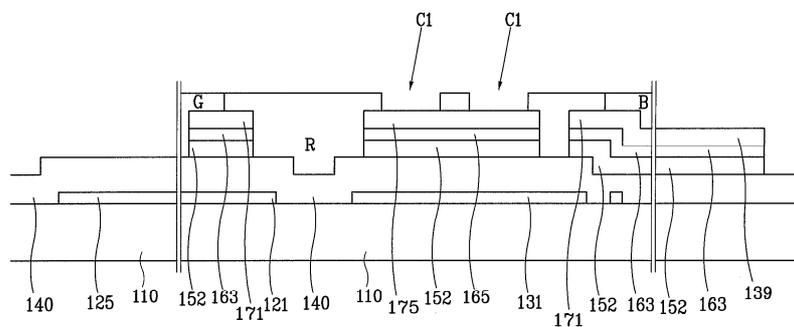
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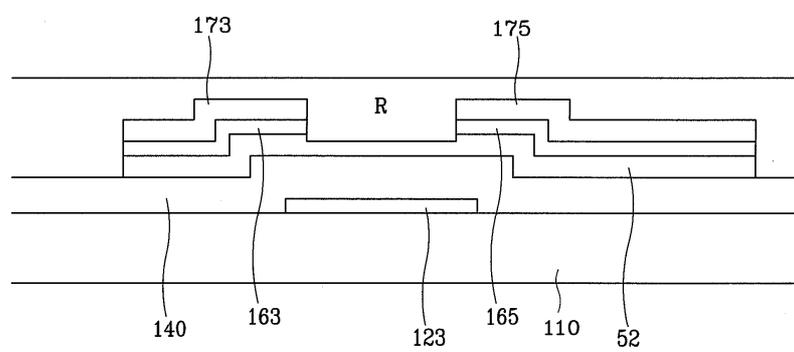
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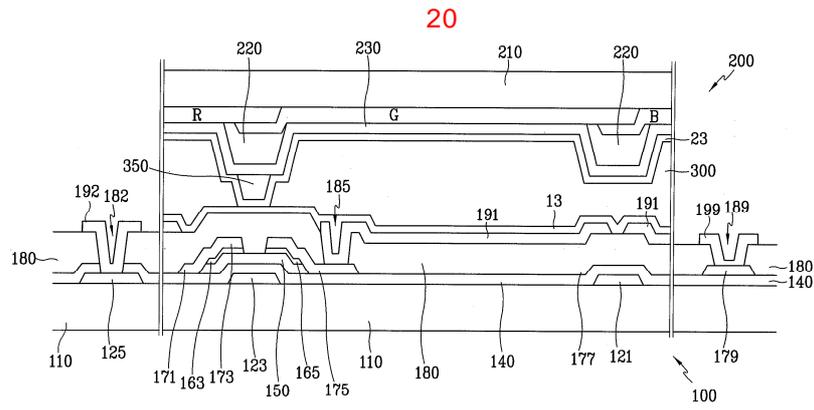


18b



18c





专利名称(译)	用于显示装置的显示装置，制造该显示装置的方法和液晶显示装置		
公开(公告)号	KR1020040081947A	公开(公告)日	2004-09-23
申请号	KR1020030016550	申请日	2003-03-17
[标]申请(专利权)人(译)	三星电子株式会社		
申请(专利权)人(译)	三星电子有限公司		
当前申请(专利权)人(译)	三星电子有限公司		
[标]发明人	KIM DONGGYU 김동규 KIM SHIYUL 김시열 KIM SANGSOO 김상수		
发明人	김동규 김시열 김상수		
IPC分类号	G02F1/1339 G02F1/1362 G02F1/1368 G09F9/30 G02F1/1335 G09F9/35		
CPC分类号	G02F1/13394 G02F1/133512 G02F2001/136222		
其他公开文献	KR100945579B1		
外部链接	Espacenet		

摘要(译)

首先，在将包括黑色涂层的有机绝缘材料涂覆在基板上并使其曝光并显影并形成黑色矩阵之后，层叠上部公平的导电材料并形成公共电极。随后，形成具有倾斜表面的突起，同时在光刻中涂覆和图案化光敏有机绝缘体并在黑色矩阵的上部形成基板间隔材料，液晶分子在像素区域中分隔。基板间隔材料，液晶，突起，分割方向，黑色矩阵。

